



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent application of :
Yeong-Kwan KIM et al. : Group Art Unit 1762
Serial No. 09/414,526 : Examiner M. Cleveland
Filed October 8, 1999 :
METHOD FOR MANUFACTURING A THIN FILM

#12/B
Hqda
8/30/01
(NE)

AMENDMENT AFTER FINAL

Honorable Commissioner For Patents
Washington, D.C. 20231

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AUG 30 2001
TC 1700

Sir:

July 11/11/01

In response to the final Office Action dated February 26, 2001, the period for response having been extended by a concurrently filed Petition For Extension Of Time, the following amendments and remarks are submitted:

In the Claims¹

Kindly rewrite Claim 1 to read as follows:

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1. (Twice amended) A method for manufacturing a thin film, comprising:
loading a substrate into a reaction chamber;
uniformly terminating dangling bonds on the surface of the substrate with
a specific atom;
chemically adsorbing a first reactant onto the terminated substrate by
injecting the first reactant into the reaction chamber;

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¹ A copy of any revised claims showing additions and deletions thereto is attached as ATTACHMENT "A".